

# Lecture 8

## Local and Global Interconnects

## Modeling Interconnects – capacitance of a single wire-

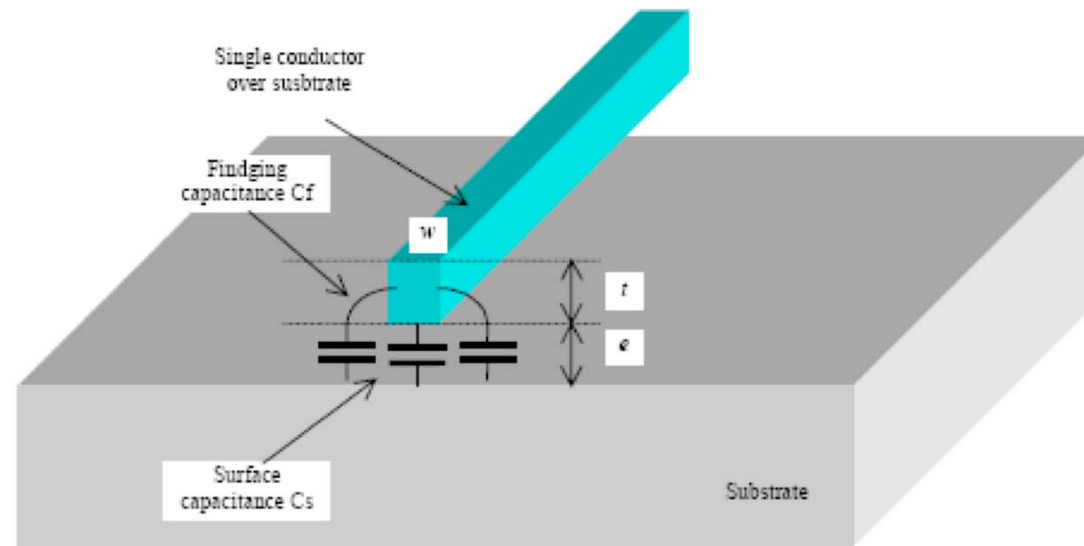


Figure 5-18: One conductor above a ground plane

$$C = C_s + 2 \cdot C_f = \epsilon_0 \epsilon_r \left( 1.13 \cdot \frac{w}{e} + 1.44 \cdot \left( \frac{w}{e} \right)^{0.11} + 1.46 \cdot \left( \frac{t}{e} \right)^{0.42} \right) \quad (5-2)$$

C = total capacitance per meter (Farad/m)

C<sub>s</sub> = surface capacitance (Farad/meter)

C<sub>f</sub> = fringing capacitance (Farad/m)

$\epsilon_0 = 8.85 \cdot 10^{-12}$  Farad/m

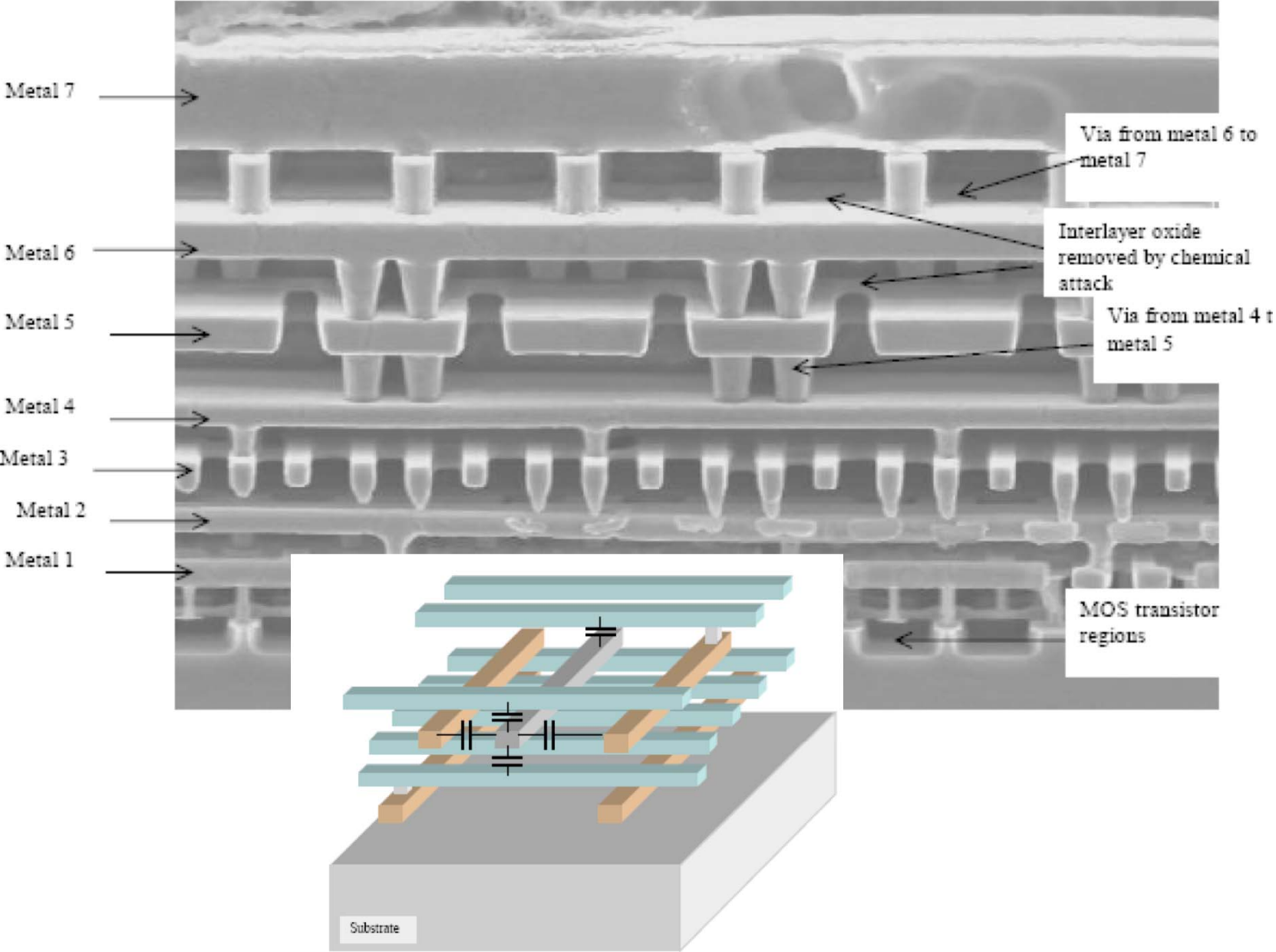
$\epsilon_r = 3.9$  for SiO<sub>2</sub>

w = conductor width (m)

t = conductor thickness (m)

e = dielectric thickness (m)

# wires everywhere!



# Modeling Interconnects – capacitance of two wires-

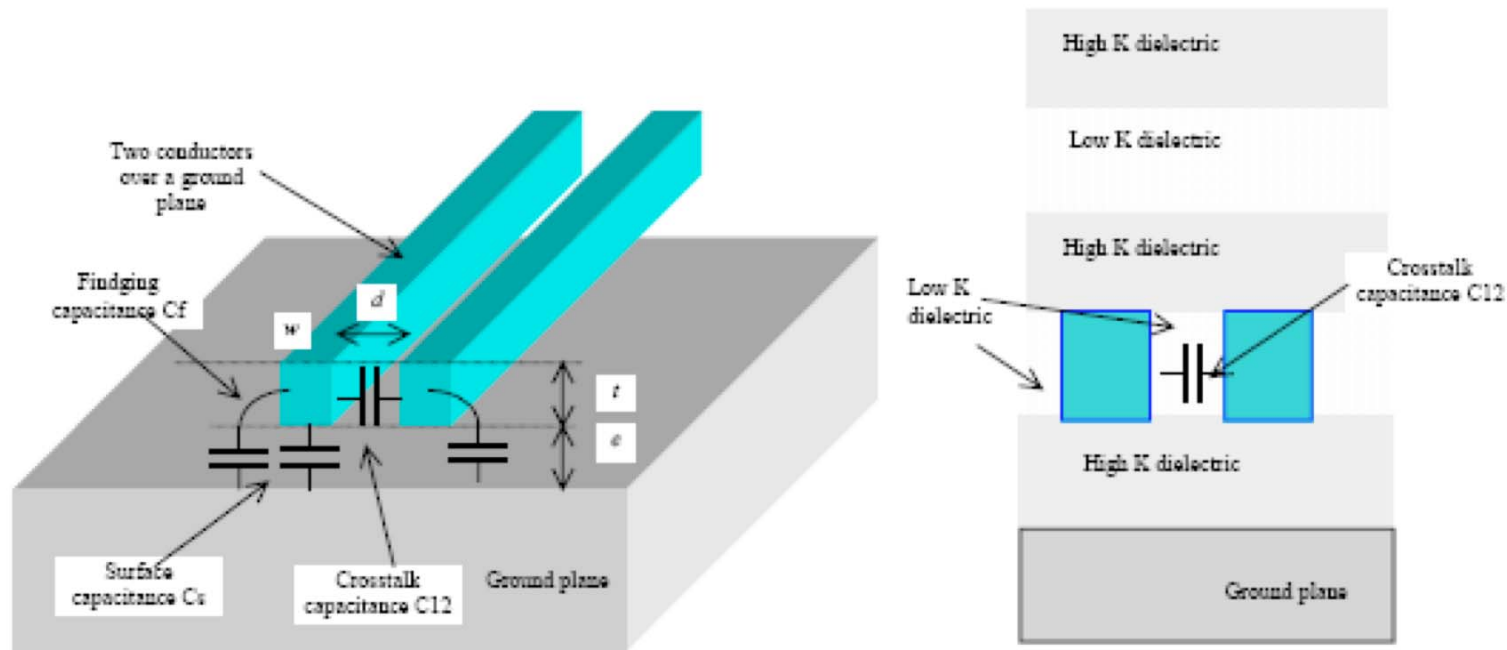


Figure 5-20: Two conductors above a ground plane

$$C = C_s + C_f = \epsilon_0 \epsilon_r \left( 1.10 \frac{w}{e} + 0.79 \left( \frac{w}{e} \right)^{0.1} + 0.46 \left( \frac{t}{e} \right)^{0.17} \left( 1 - 0.87 e^{-\frac{d}{e}} \right) \right) \quad (5-3)$$

$$C_{12} = \epsilon_0 \epsilon_{r_{lowK}} \left( \frac{t}{d} + 1.2 \left( \frac{d}{e} \right)^{0.1} \cdot \left( \frac{d}{e} + 1.15 \right)^{-2.22} + 0.253 \ln \left( 1 + 7.17 \frac{w}{d} \right) \cdot \left( \frac{d}{e} + 0.54 \right)^{-0.64} \right) \quad (5-4)$$

C = conductor capacitance to ground per meter (Farad/m)

Cs = surface capacitance (Farad/meter)

# Modeling Interconnects –layout capacitance example-

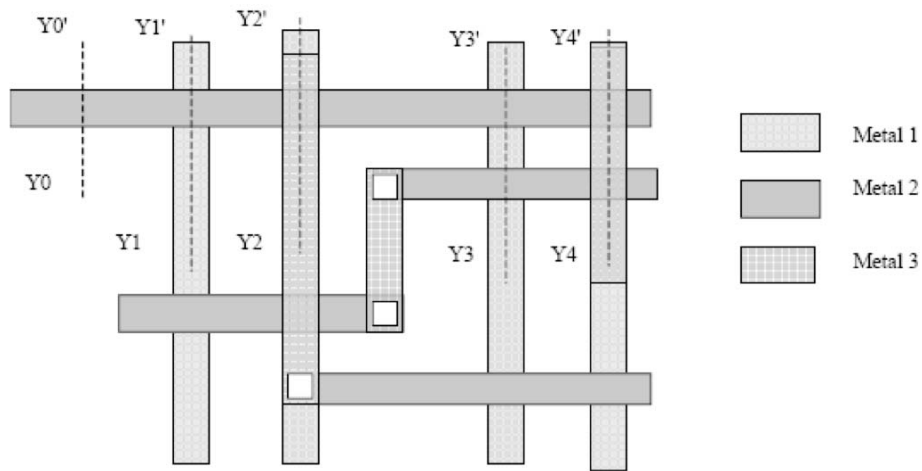
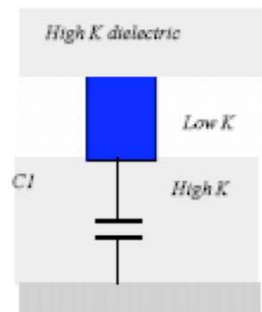
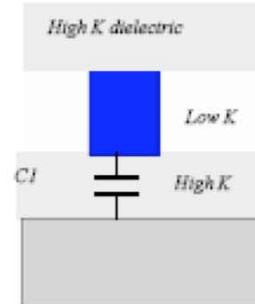


Figure 5-21: Example of interconnects routed in metal 1, 2 and 3



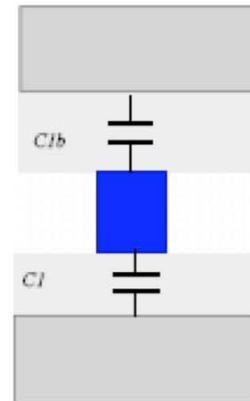
One conductor above substrate  
(Y0-Y0')

$$C=C1=70\text{fF}/\text{mm}$$



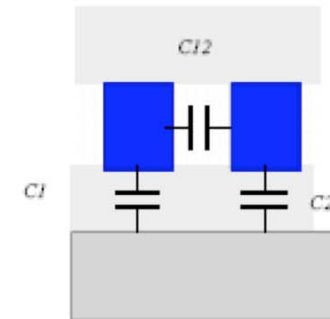
One conductor, one plane  
(Y1-Y1')

$$C=C1=120\text{fF}/\text{mm}$$



One conductor, two planes  
(Y2-Y2')

$$C=C1+C1b=150\text{fF}/\text{mm}$$



Two conductors, one plane  
(Y3-Y3')

$$C=C1=90\text{fF}/\text{mm}$$

$$C12=50\text{fF}/\text{mm}$$

# Interconnect resistance

$\rho_{Ag}$	Gold resistivity	Bonding between chip and package	$2.20 \cdot 10^{-6} \Omega \cdot \text{cm}$
$\rho_{tungsten}$	Tungsten resistivity	Contacts	$5.30 \cdot 10^{-6} \Omega \cdot \text{cm}$
$\rho_{Ndifff}$	Highly doped silicon resistivity	N+ diffusions	$0.25 \Omega \cdot \text{cm}$
$\rho_{Nwell}$	Lightly doped silicon resistivity	N well	$50 \Omega \cdot \text{cm}$
$\rho_{si}$	Intrinsic silicon resistivity	Substrate	$2.5 \cdot 10^5 \Omega \cdot \text{cm}$

Table 5-3: Resistivity of several materials used in CMOS circuits

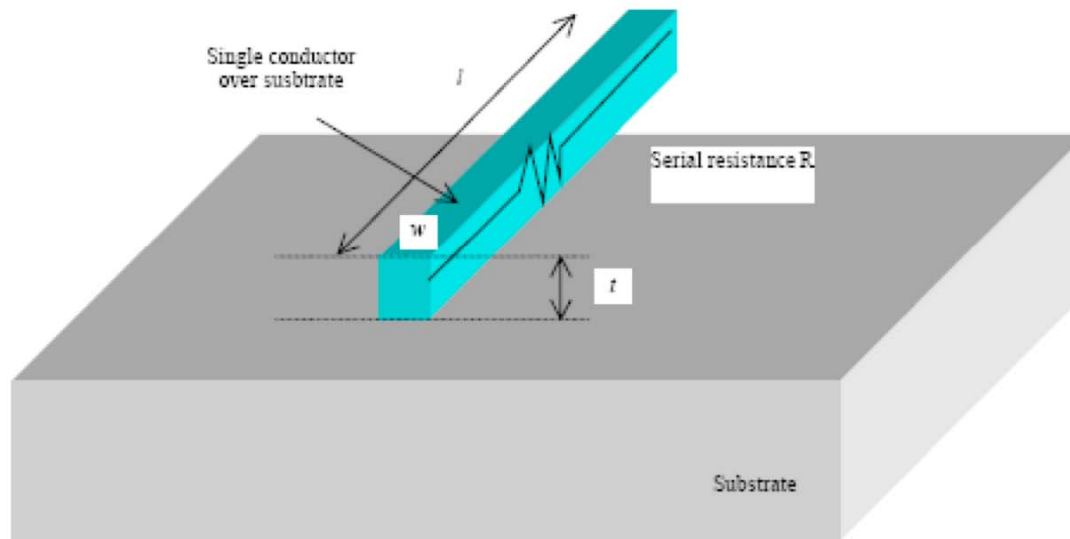


Figure 5-26: Resistance of a conductor

$$R = \rho \frac{l}{w \cdot t} \quad (\text{Equ. 5-5})$$

where

$R$ =serial resistance (ohm)

$\rho$ =resistivity (ohm.m)

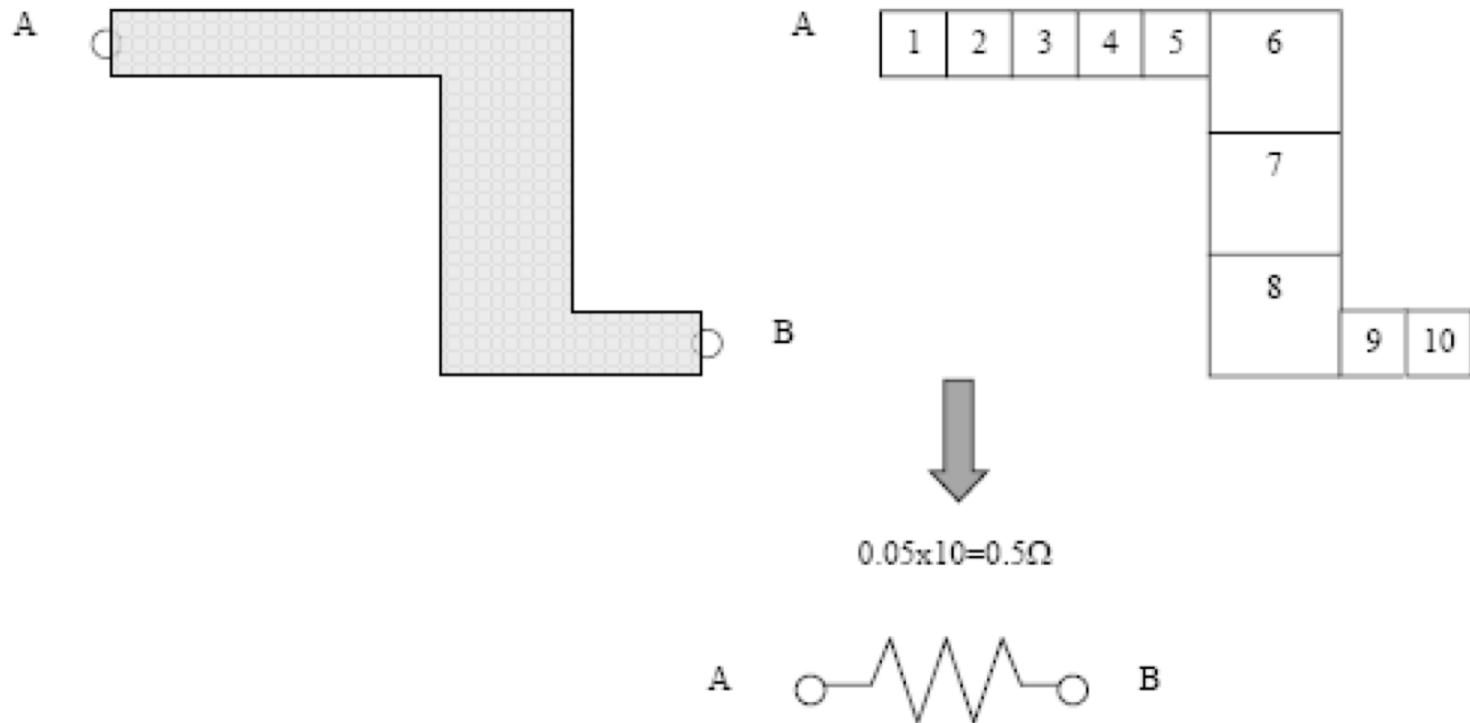
$w$ = conductor width (m)

$t$ = conductor thickness (m)

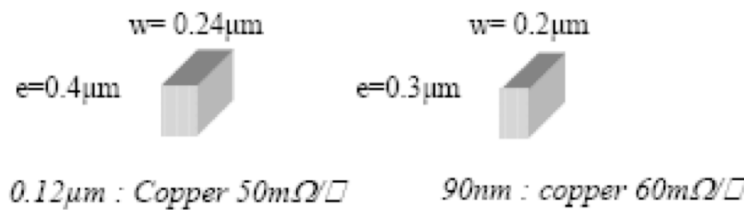
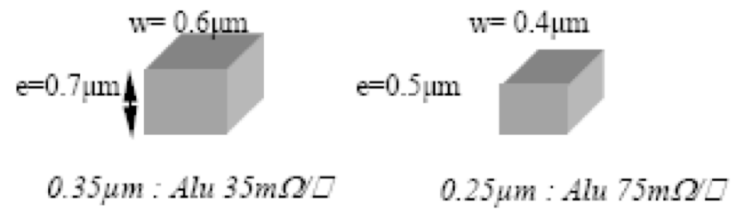
$l$  = conductor length (m)

$d$  = conductor distance (m)

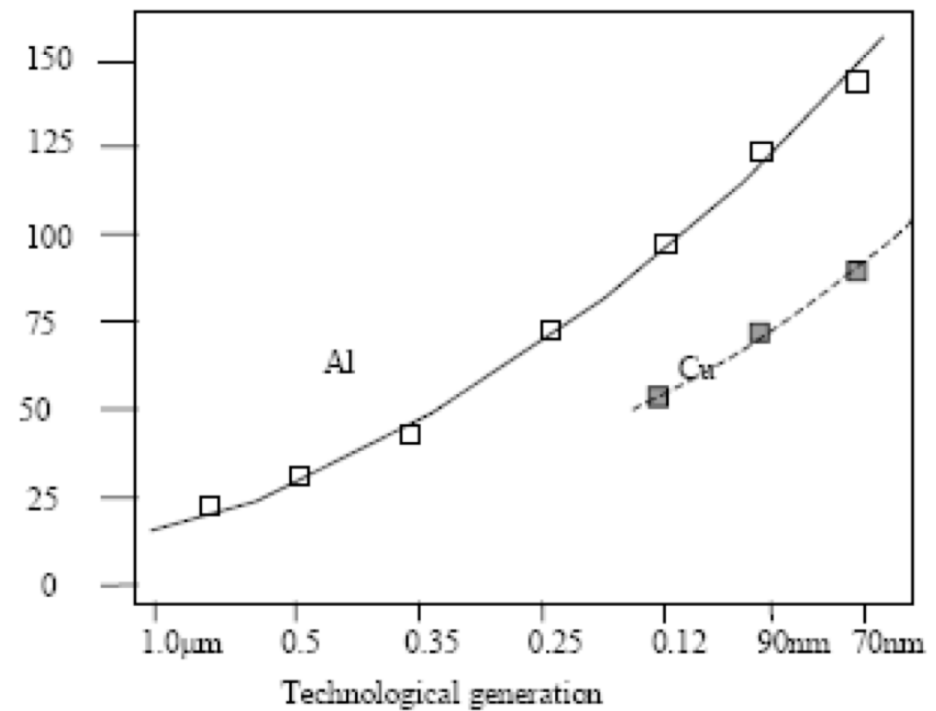
# Estimating resistance of a wire –measuring squares-



# Interconnect resistance scaling



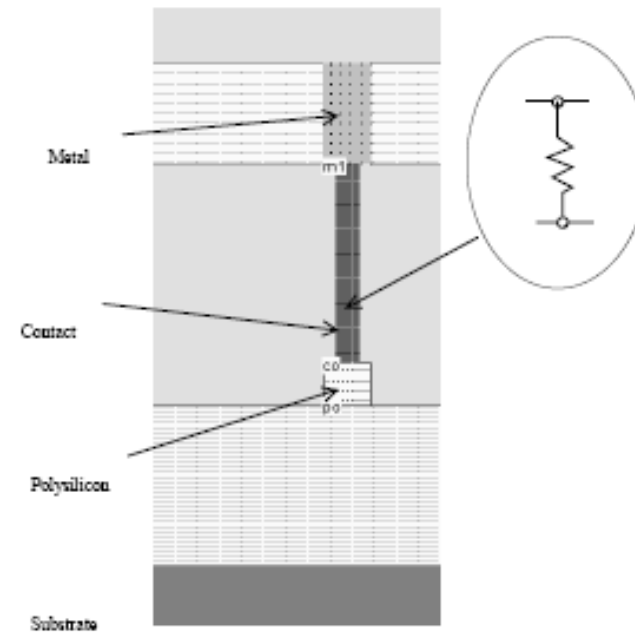
Interconnect resistance/nm





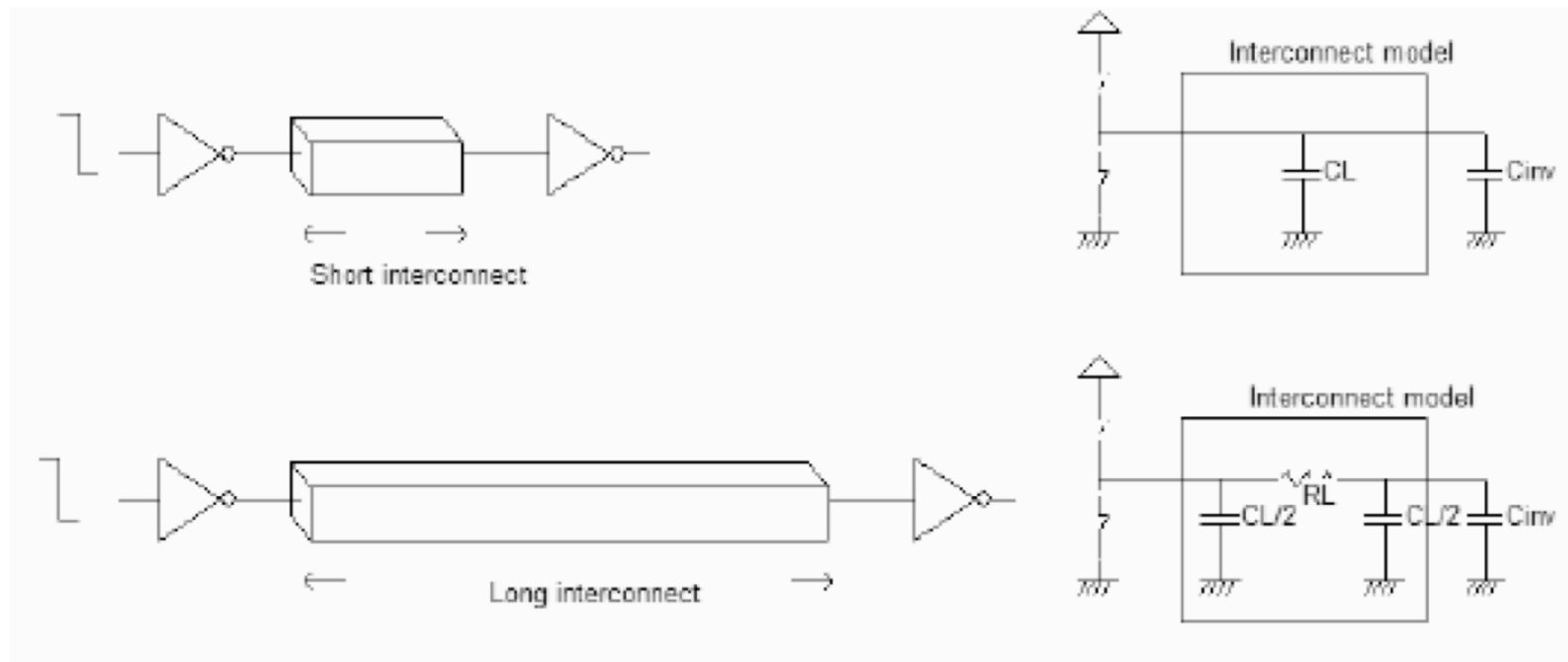
# Via resistance

Technology	0.7 $\mu\text{m}$	0.12 $\mu\text{m}$	90nm
Contact resistance	0.5 $\Omega$	15 $\Omega$	20 $\Omega$
Via	0.3 $\Omega$	4 $\Omega$	8 $\Omega$
Upper via	-	1 $\Omega$	3 $\Omega$



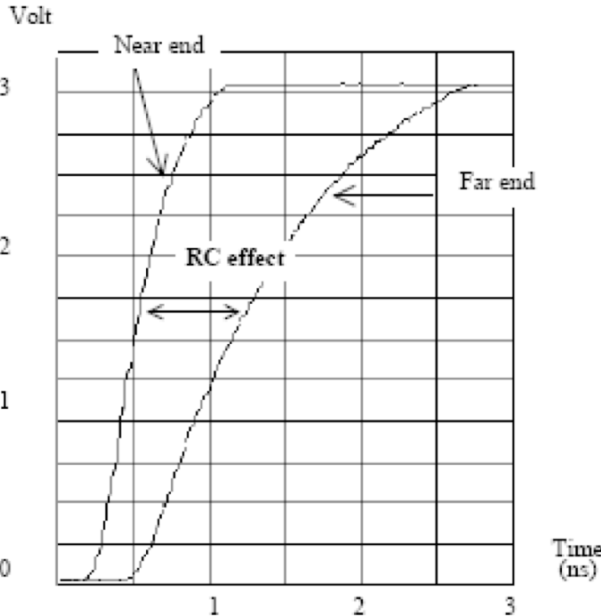
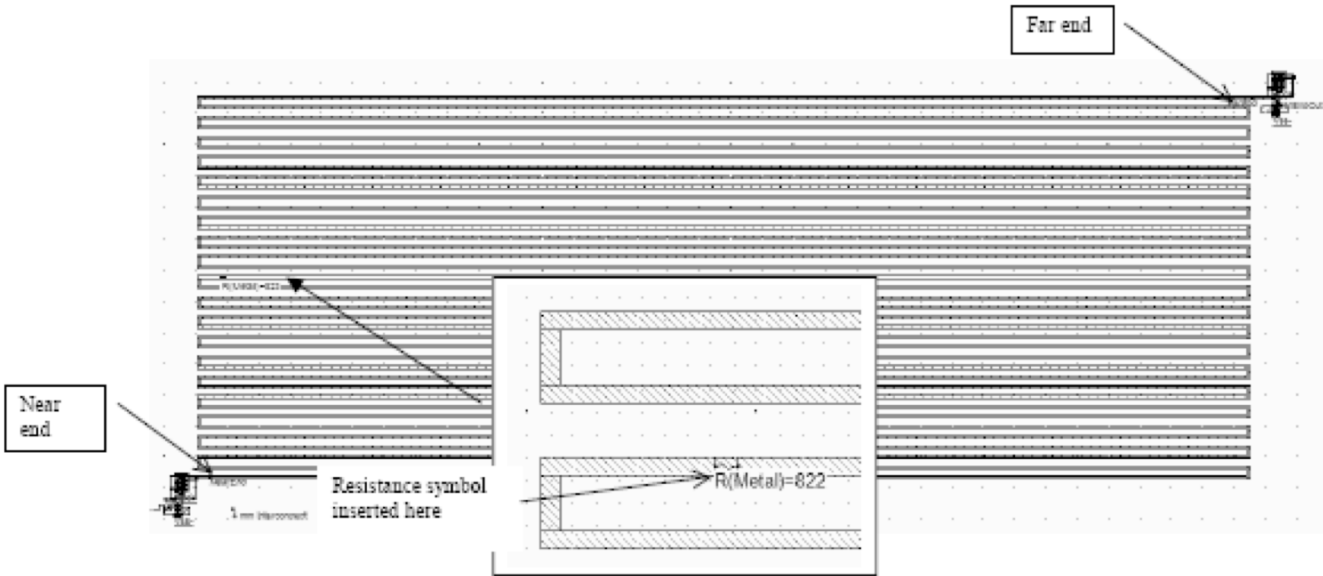
# Modeling interconnects

## Lumped parameter: (C)



## Distributed: (R-C)

# Simulation



(a) 10mm, metal 3, 0.35μm technology

# Modeling interconnects (II)

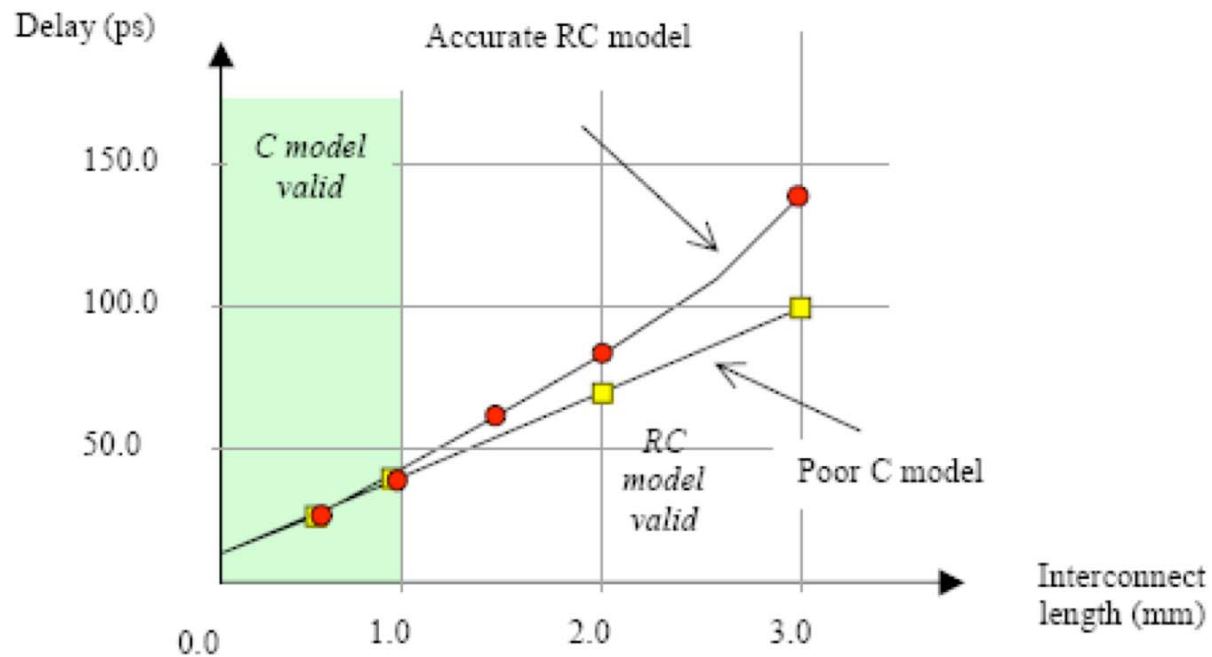
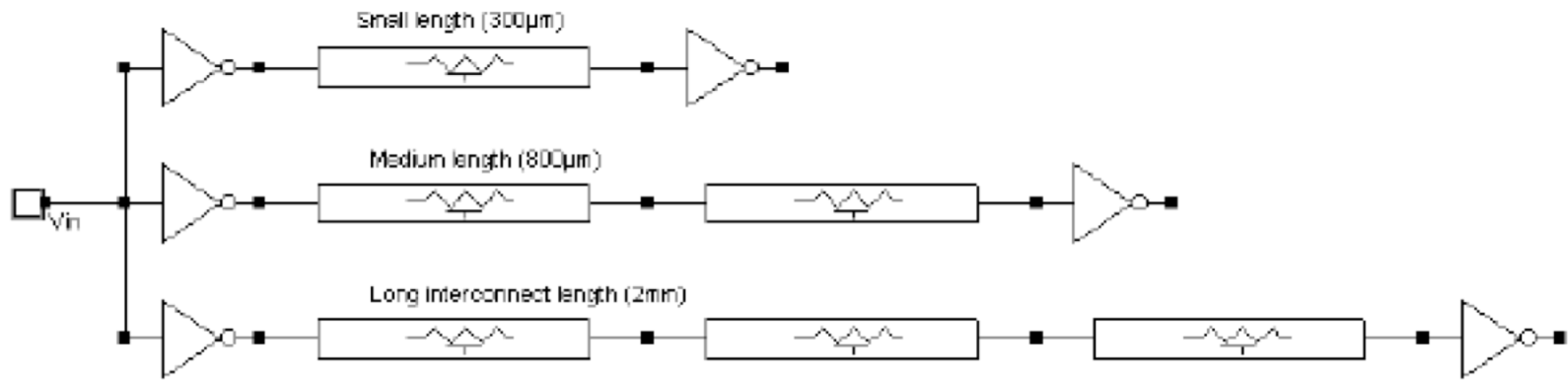
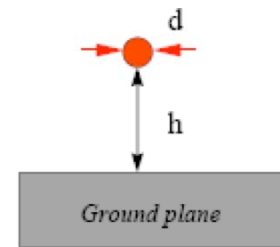
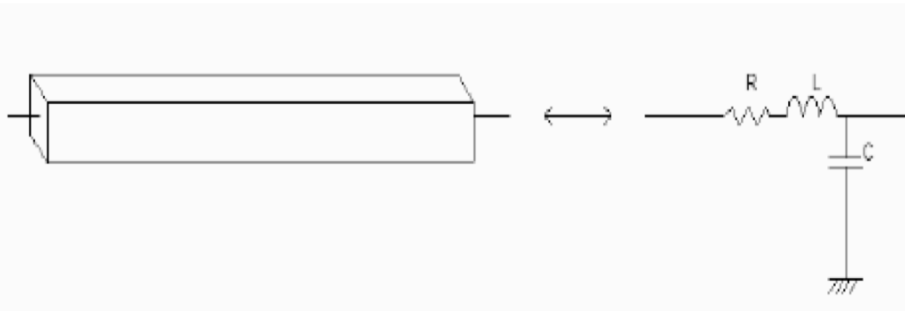


Figure 5-43: Below 1mm, the C model is valid. Above 1mm, the RC model should be considered in 0.12µm CMOS technology

# how about inductance?



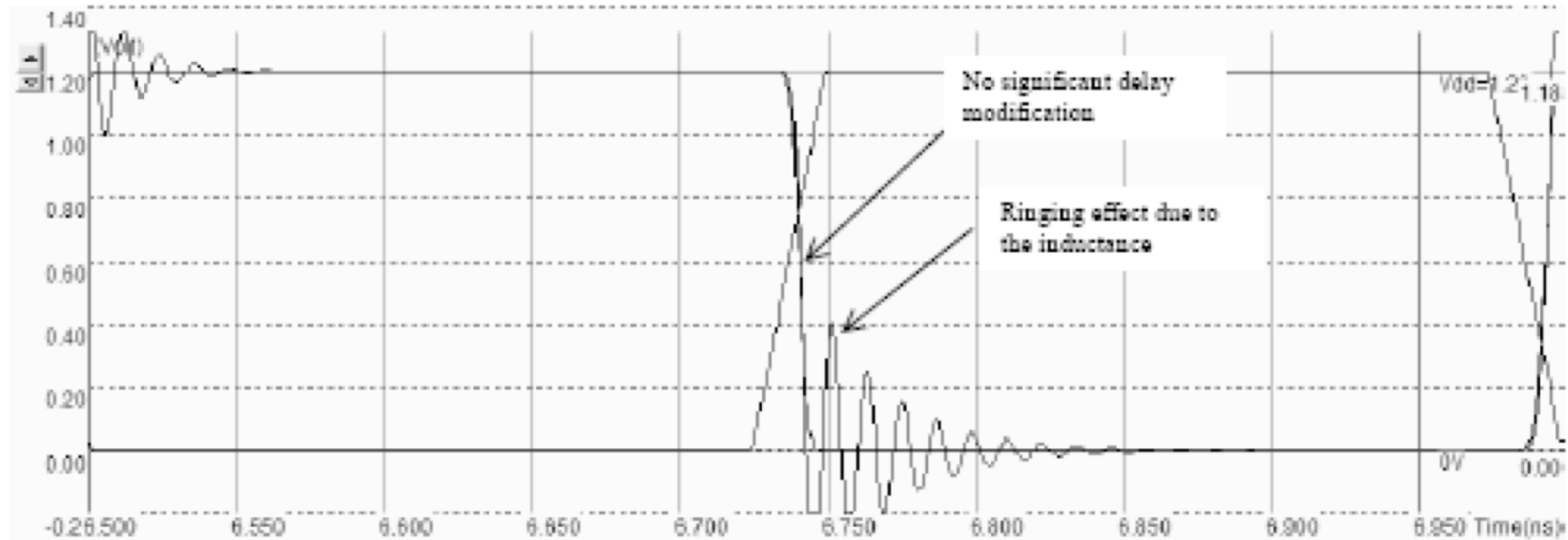
$$L = \frac{\mu_0}{2\pi} \ln\left(4 \frac{h}{d}\right) \quad (\text{Equ. 5-7})$$

with

$\mu_0 = 1.257 \times 10^{-6}$  H/m for most materials (Al, Cu, Si, SiO<sub>2</sub> and Si<sub>3</sub>N<sub>4</sub>)

d = wire diameter (m)

h = height of the wire vs. ground (m)



# transistor and interconnect models

## A Pair of Inverters

